



AF 11746

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Yuji ONO et al.

Serial No.: 09/940,788

Corres. and Mail

Group Art Unit: 1746

Filed: August 29, 2001

BOX AF

Examiner: Joseph L. Perrin

P.T.O. Confirmation No.: 4613

For: **SINGLE WAFER TYPE SUBSTRATE CLEANING METHOD AND APPARATUS**

RESPONSE UNDER 37 CFR §1.116
- EXPEDITED RESPONSE -
GROUP ART UNIT 1746

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA, 22313-1450

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June 4, 2003

Sir:

In response to the Office Action dated **March 11, 2003**, please amend the above-identified application as follows: